EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
Li.	256585	(measur\$3 or test\$3) near7 (surface or workpiece)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:03
L2	33550	(measur\$3 or test\$3) near9 interfer\$4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:01
L3	1451	1 and 2 and ((first or second or main or primary) near4 (beam or emit\$4 or radiat\$3))	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:51
L4	10953	(reference near4 (test\$3 or measur\$3 or surface)) near9 (adjacent or next or relative)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:06
Ľ5	191	3 and 4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:17
L6	119	5 and (beam adj splitter) and interference	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:14
L7	100	6 and ((test\$3 or measur\$3) near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:39
L8	29	7 and tube and (open\$3 or holes)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:50
L9	6	8 and (plane near2 mirror)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:42
L10	92	(measur\$3 or test\$3) near2 probe near2 interfer\$4	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:58
L11	1	1 and 10 and 4 and ((first or second or main or primary) near4 (beam or emit\$4 or radiat\$3))	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:51
L12	2	("5907400").PN.	USPAT; EPO; JPO; DERWENT	OR	OFF	2006/02/28 15:57
L13	0	4 and 12	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 15:58
L14	105109	(measur\$3 or test\$3) near4 (interfer\$4 or beam or radiat\$3)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:02
L15	5447	(align\$3 or parallel\$3 or along) near7 ((measur\$3 or test) near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:03

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L16	297	14 near9 15	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:04
L1/	55	3 and 10	EPO; JPO; DERWENT	OR		2006/02/28 16:04
L18	20	4 and 17	USPAT; EPO; JPO; DERWENT	OR	ON	2006/02/28 16:10

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US 6950196 B2	Methods and systems 356/630	356/237.2; 356/369
US 6946394 B2	Methods and systems 438/680	356/237.2; 356/237.3; 356/600; 3
US 6919957 B2	Methods and systems 356/237.2	
US 6917433 B2	•	257/E21.53; 324/229
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US 6917419 B2	Methods and systems 356/237.2	355/72; 355/76
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